



PATENT

1763

Examiner: Sylvia MacArthur

Confirmation No.: 4127

For: Integrated Semiconductor
Substrate Bevel Cleaning
Apparatus and Method

CERTIFICATE OF MAILING
37 CFR 1.8

Date 6/25/03 Signature B. Todd Katten

PETITION FOR ONE-MONTH EXTENSION OF TIME

This form is filed in duplicate. The Commissioner is authorized to charge the fee of \$110.00 and any additional fees which may be required for this submission to Deposit Account No. 20-0782/4969/CMP/ECP/NAN.

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